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APPLICANTS

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U. S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Bajaj, R. et al., Materials Research Society Symposium Proceedings, Vol. 337, "Effect of Polish Pad Material Properties on Chemical Mechanical Polishing (CMP) Processes, 4/4/94, pages 637-644.

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